Novel Photolabile Protecting Group for Carbonyl Compounds

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## Overview

- Background & History
- Synthesis
- Protection Cycle
- Substrate Selectivity
- Evidence for Proposed Mechanism
- Stability
- Conclusion

- The value of protecting groups in synthesis is difficult to overstate
- One of the major difficulties lies in their susceptibilities to reaction conditions and in differentiating similar moieties that are protected
- One solution to this is to design a protecting group that makes use of uncommon reaction conditions

# History of Photolabile Protecting Groups

- Research into this type of protecting group goes back many decades
- Groups that can be simply and efficiently protected include: alcohols, amines, amides, carboxylic acids and phosphates
- Despite the large volume of photolabile groups available, it has been challenging to design one for the aldehydes and ketones
- Several attempts have been made, with varying degrees of success
- Most of these protecting groups are susceptible to reactive organometallic reagents and reducing reagents, and are also non-trivial to synthesize



- Synthesized in one step from 5methoxysalicylic acid
- Easily scaleable

#### **Protection Cycle**





**Table 1.** Protection and Photorelease of the Carbonyls

entry	carbonyl compounds	protection yield (%)	deprotection yield (%)	irradiation time (min)
1	1a	$99^a$	$90^e$	60
2	1b	$91^a$	$89 \; (Z/E = 1.4)^e$	40
3	1c	$95^a$	$85^{f}$	50
4	1d	$>99^{a}$	$74^e$	60
5	1e	$99^a$	$89^e$	60
6	1f	$97^b$	$80^{g}$	80
7	$1 \mathbf{g}$	$93^c$	$84^e$	80
8	1h	$91^c$	$86^g$	60

<sup>*a*</sup> **2** (0.3 mmol), *p*TsOH (0.02 mmol), and carbonyl compound (0.2 mmol) in 1.0 mL of benzene, 23 °C, 24 h. <sup>*b*</sup> **2** (0.3 mmol), *p*TsOH (0.02 mmol), carbonyl compound (0.2 mmol), and CuSO<sub>4</sub> (0.8 mmol) in 1.0 mL of benzene, 23 °C, 24 h. <sup>*c*</sup> **2** (0.3 mmol), *p*TsOH (0.02 mmol), carbonyl compound (0.2 mmol), and P<sub>2</sub>O<sub>5</sub> (0.8 mmol) in 1.0 mL of benzene, 23 °C, 24 h. <sup>*d*</sup> Irradiated with a 450 W medium-pressure mercury lamp equipped with a Pyrex filter sleeve. <sup>*e*</sup> Isolated as the oxime derivatives. <sup>*f*</sup> Isolated as the semicarbazone derivative. <sup>*g*</sup> Isolated as the ketone without derivatization.



- To test the proposed deprotection mechanism of the zwitterionic intermediate the groups in the trityl position were varied
- When one phenyl group was transposed to a proton, let to a deprotection yield of 33%
- When both phenyls were changed to methyl groups, the deprotection yield dropped to less than 6%
- Further testing revealed that the meta-methoxy group is vital to the deprotection, with no deprotection detected in the absence of the methoxy group

#### Stability to reaction conditions

entry	$reagent^a$	$\operatorname{solvent}$	conditions	<b>3a</b> (%)°
1	$PhLi^{b}$	THF	−78 to 23 °C, 6 h	100
2	$LiAlH_4$	$C_6H_6$	23 °C, 24 h	100
			reflux, 2 h	100
3	t-BuOK	MeCN	23 °C, 24 h	100
4	DDQ	MeCN	23 °C, 24 h	100
5	AcOH	MeCN	23 °C, 24 h	100
		$C_6H_6$	23 °C, 24 h	100
		$C_6H_6$	reflux, 2 h	94
6	TFA	MeCN	23 °C, 24 h	98
		$C_6H_6$	23 °C, 24 h	93
		$C_6H_6$	reflux, 2 h	89
7	pTsOH	MeCN	23 °C, 24 h	75
		$C_6H_6$	23 °C, 24 h	95
		$C_6H_6$	reflux, 2 h	92
8	HCl (37%)	MeCN	23 °C, 24 h	99
		$C_6H_6$	23 °C, 24 h	96
		$C_6H_6$	reflux, 2 h	93
9	$\mathrm{HCl}(1\ \mathrm{N})^d$	THF	40 °C, 24 h	100

Table 2. Stability of 3a under Various Conditions

<sup>*a*</sup> **3a** (0.01 mmol) in 1.0 mL of MeCN or 0.5 mL of benzene treated with reagent ( $\geq 0.1$  mmol). <sup>*b*</sup>**3a** (0.05 mmol) in 1.0 mL of dry THF treated with 0.4 mL of PhLi (2.0 M Bu<sub>2</sub>O solution) at -78 °C. <sup>*c*</sup>Yields determined by <sup>1</sup>H NMR of the crude reaction mixture after workup. <sup>*d*</sup>**3a** (0.04 mmol) in 0.6 mL of THF with 0.2 mL of 1 N HCl.

### Conclusion

- A novel protecting group using the unique photochemical strategy
- An extremely stable protecting group that contains minimal functionality to interfere with the substrate
- High efficiency of protection and deprotection